THE MISSING LINK IN TELECOM MEMS, TODAY.™

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GLASTEST Universal Interface Test Management for EG2001

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Metallic Membranes



Hi-Q Inductors, Integrated Passives, Antennas



3D Electromagnetic Simulation



Wafer Level Packaging

Electrostatic and Electromagnetic Actuators



PHS MEMS have a large variety of devices to test, the ability of a system to accommodate was the motor of our investigation.



One cost effective solution is to extend the testing life of EG 2001 prober.



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What is the premier objective when running a test sequence ?

- •Accuracy
- •Productivity
- •Probe card management
- •Access to your data
- •Engineering use



GlasTest is a user friendly interface added to existing EG2001 wafer prober.

Adapted for production and engineering, GlasTest control the wafer prober and instruments via the GPIB interface.

Developed under LabVIEW environment, it is quickly installed on a personal computer running windows NT.







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GlasTest





Physical configuration where all parameters are recorded for all set up. (eg : die size, wafer diameter, first die, microprobing...)

| 2001X Z Stage Settings : 2001X Misc. Settings : | X Misc. Settings : | |
|---|--|--|
| ns) Z Up Limit (0.1 mils) 34000 Enable Enhanced Profile | | |
| 3 Z Down Limit (0.1 mils) 3 2000 Enable Screen / Lamp Saver | | |
| 000 Z Overtravel (0.1mils) 0 2001× Alignment Setting | gs : | |
| 000 Z Clearance (0.1 mils) 3 500 Set Align Scan Speed |) 5 | |
| 00 Z Undertravel (0.1mils) 0 Enable stop is auto align fails | | |
| 1 Z Auto Align Height 3 2000 Select Auto Align Mode |) | |
| 1 Enable 30 mil drop at load position 🗖 Threshold (Norm/Low/High) |) | |
| 90 Enable Double Touchdown 🗖 Enable Auto Light Adjust | | |
| 2001X Mapping Settings : | | |
| Product mapping (should contain all dies - for display use only) | _ | |
| Test mapping (all dies that need to be tested) | | |
| 8 | | |
| Test with auto mapping file if found ? | | |
| r) | 2001X 2 Stage Settings : 2001X Misc. Settings : 18) 2 Up Limit (0.1 mils) 4000 2 Down Limit (0.1 mils) 2000 Enable Enhanced Profile 2 Down Limit (0.1 mils) 2000 Enable Screen / Lamp Saver 00 2 Overtravel (0.1 mils) 0 2001X Alignment Setting 00 2 Clearance (0.1 mils) 500 Set Align Scan Speed 10 2 Auto Align Height 2000 Enable stop is auto align fails 1 2 Auto Align Height 2000 Select Auto Align Mode 1 Enable 30 mil drop at load position Threshold (Norm/Low/High) 5 90 Enable Double Touchdown Enable Auto Light Adjust 1 Product mapping (should contain all dies - for display use only) 5 1 Product mapping (all dies that need to be tested) 5 1 Test with auto mapping file if found ? Test with auto mapping file if found ? | |



Config. selector

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| Files Instruments definitions | | 2001× GPIB | | | |
|---|----------------------|--|--|--|--|
| lumber of GPIB Instruments | 0 Prober GPIB Adr | ress | | | |
| 0 Clear | | Raw Measure files save path | | | |
| | Standard file strue | icture: Meas. Dir.\BatchName\BatchName_NN.mes) | | | |
| | 1 | | | | |
| | | | | | |
| | Record files in thi | is directory : | | | |
| | 8 | <u>ط</u> | | | |
| | | | | | |
| Measurement Parameters Limits (Requested for yield calculations, Ink options, Re Number of measurement parameters | est options) | | | | |
| 0 Clear | | | | | |
| arameter name Active ? Low | er Limit Upper Limit | | | | |
| | 00E+0 + 0.000E+0 | | | | |

Network path declaration to recover recorded files.

Up to 30 instruments can be connected via GPIB bus.



Inline or offline inking.

Limits are specified in the test interface menu. (multi-parameters combinations).

| Die Inking options (alpha version only s | ipport inker one) | |
|--|-------------------|--|
| ctivate Die Inking | | |
| k pulse width (ms) | 5 | |
| k Z chuck height (0.1 mils) | ÷) 2000 | |
| ker counter limit before warning | 0100000 | |
| ies Already inked with this cartridge | 0 | |
| | Reset | |
| k wafer online ? | | |
| k with auto mapping files | - | |
| k die delay folowing die under test | 0 | |
| | | |



- Cleaning rate optimization :
 - maximize yield
 - minimize cost
- Cost identified
 - capital
 - labor
 - throughput
 - maintenance





• Cleaning frequency influence



Too much cleaning increase production costs Not enough cleaning affects yield Find your optimum cleaning rate, Prober Statistic Stability Control can help.

Yield impact is defined as classifying a bad die when it is good.



Cleaning pad surface is declared from edge declaration, cleaning routine matches whatever the dimension or the location.

Specific algorithm for ITS cleaning products.





Cleaning probes impacts from 20 to 256 touchdowns (5 mils clean pitch)



Separate data files are created for each probe card :

- #Touchdowns
- #Clean operations
- Clean pitch
- Cleaning frequency/mode
- Maintenance frequency
- First installation date
- EG identity listing



- Repeatability and reproducibility gage study perform for multi parameter applications.
- Measurement capability
 - C = Tolerances / Dispersion



Working standard generation, upper and lower limits calculation with SPC methodology.

Control charts are followed with an adjustable frequency

Parametric Western Electric alarm rules



| Clastest Config Editor 1.2 | Suizi Canabilitá | Western Flectric | Micro probing | Admin stuff | |
|--|------------------|------------------|---------------|-------------|---------------|
| | Sur Supasiire | | maile browing | | |
| 🔽 Activer la prise en charge du suivi de capabilité mesure (CMC) | | | | | |
| Fichiers support CMC | | | | | |
| Fichier MAPPING décrivant les puces suivies | 2 | | | | |
| Fichier de données CMC brutes | 2 | | | | |
| Fichier de données CMC traitées | 8 | | | | <u> </u> |
| Limites de controle | | | | | |
| 0 Clear | Moyenne Sup | Moyenne Inf | Etendue Sup | Etendue Inf | Moyenne Vraie |
| | 0,0000E+0 | 0,0000E+0 | 0,0000E+0 | 0,0000E+0 | 0,0000E+0 |
| | | | | | |
| | | | | | |
| | | | | | |
| | | | | | |
| | | | | | |

Configure reference data and declare upper and lower control limits



Operator is immediately advise of the prober accuracy after the working standard measurement.





Control charts visualization



• In line and final test perform only on selected dies.





Real time wafer status





From sort to packaging :

- Testing
- Dicing
- Inspection
- Pick & place
- Assembly
- Functional test

The problem : wafer map converters Map file format is adapted to the following steps in the flow.



Feedback for maintaining process under control

Die functionality

Yield enhancement



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Engineering functions

Virtual mode allows test engineers to verify the set up, and instruments test's routines without being connected to a prober.

Log viewer.



Remote test screen monitoring via internet browser.



Production screen as clear as possible for operating.

| 🔁 Glastest 1.2 Login | informations | | | | × | |
|---|--------------|--|----------------------------|--------|------|--|
| Lastname | Sandri | | mardi 21 mai 2002 14:00:0E | | | |
| Firstname | Philippe | | mardi 21 mai 2002 14:09:05 | | | |
| Employe number 🖞 | 1033 | | | | | |
| No de Lot : | W458 | | \bigcirc | tro1 | | |
| Select all 25 wafers | 3 | | | Cancel | Next | |
| Select wafers to test : 1 2 3 4 5 6 7 8 9 10 11 12 13 14 15 16 17 18 19 20 21 22 23 24 25 | | | | | | |
| Comments | | | | | | |
| Test Wafer 1, 4 and 9 | | | | | | |



Conclusion

GlasTest has multiple Economic and Technical Advantages

Flexible

Accommodates a large variety of devices. Stand Alone or network management system. GlasTest provides development and production support.

Accurate

all quality requirements : Stability Control Chart & SPC. working in a Know Good Die environment. cleaning probe card routine control.

Revenue increase increase yield, throughput and probe card life



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